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Davis et al.

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[54] **SPIN COATING BOWL EXHAUST SYSTEM**

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[51] **Int. Cl.⁶** **B05C 11/02**

[57] **ABSTRACT**

[52] **U.S. Cl.** **118/52; 118/56; 118/319;**
118/320

An apparatus for exhausting coating materials used in the process of spin coating a top surface of a wafer, the wafer having an edge and a bottom surface that is supported and rotated by a rotatable chuck attached by a shaft to a spin motor. The apparatus includes a bowl having an exhausted drain configured to receive excess liquid and vapor from the spin coating and an assembly configured to maintain the drain at a negative pressure differential relative to the bowl. In a preferred embodiment, a baffle is attached to the bottom to limit the flow of the liquid and vapor into the drain to a predetermined direction.

[58] **Field of Search** 118/52, 56, 319,
118/320, 500

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9 Claims, 8 Drawing Sheets

